



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **Kiyoshi MOTEKI & :  
Satoru OSHIKAWA :**

Group Art Unit: **2851**

Application No.: **09/856,384**

Examiner: **Kim, Peter**

Filing Date: **May 21, 2001**

Attorney Docket No.: **25,096 USA**

For: **Optical Apparatus, Exposure  
Apparatus, Laser Light Source, Gas  
Supply Method, Exposure Method,  
and Device Manufacturing Method**

CERTIFICATE OF MAILING

I hereby certify that this correspondence, along with any papers indicated as being enclosed, are being deposited as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on Friday, February 27, 2004.

*Patricia M. Frisoli*  
Patricia M. Frisoli

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**Response To Office Action of August 27, 2003**

Sir:

This is in response to the Office Action dated August 27, 2003. A request for a three-month extension of time to respond is included. Please amend the above-identified application as follows:

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 13 of this paper.